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Application No.: 10/603,924

JUN 15 2005

Docket No.: JCLA7109

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of :)		
)		
Shao-Chung Hu et al.)	Examiner	: NGUYEN, THANH T
)		
Serial No. : 10/603,924)	Art Unit	: 2813
)		
Filed : 06/24/2003)	Docket No.	: JCLA7109
)		
For : Post-CMP Removal Of Surface)		
Contaminants From Silicon Wafer)		

No fee is believed to be due. However, the Commissioner is authorized to charge any fees required in connection with the filing of this paper to account No. 50-0710 (Order No. JCLA7109).

AMENDMENT AND RESPONSE TO OFFICE ACTION

MAIL STOP Amendment
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Dear Sir,

The Office Action mailed on March 16, 2005 has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.